



Attorney Docket No:0492611-0545/MIT9277CONII

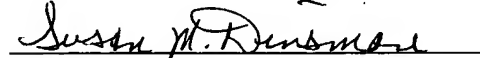
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Seleznev, *et al* Examiner: Cooke  
Serial No.: 10/799,388 Art Unit: 1754  
Filing Date: March 12, 2004  
Title: VACUUM PROCESSING FOR FABRICATION OF  
SUPERCONDUCTING THIN FILMS FABRICATED BY METAL-  
ORGANIC PROCESSING

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on May 16, 2005.

  
Susan M. Dinsmore

Sir:

**OFFICE ACTION RESPONSE UNDER 37 C.F.R. § 1.111**

This **Response to Office Action** is filed in response to the Office Action mailed March 3, 2005, rejecting claims 40-62. The cited references are Solovyov, "Ex-situ Post-deposition Processing for Large Area  $Y_1Ba_2Cu_3O_7$  Films and Coated Tapes," *IEEE Transactions on Applied Superconductivity*, 11:2939-2942 (2001) and U.S. Patent No. 5,650,378 to Iijima. The following amendments and remarks remove all grounds for rejection of the application, thereby placing it in condition for allowance.

**Amendments to the Claims** are reflected in the listing of claims that begins on page 2 of this paper.

**Remarks** begin on page 7 of this paper.